## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Debbie Prout

Applicant

: Masayuki Kuwabara

Application No.: 10/067,572

Filed

: February 4, 2002

Title

: PATTERN INSPECTION METHOD AND

INSPECTION APPARATUS

RECEIVED

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Grp./Div.

: 2621

Examiner : N/A **Technology Center 2600** 

Docket No.

: 47779/DBP/A400

## PRELIMINARY AMENDMENT

Assistant Commissioner for Patents Washington, D.C. 20231

Post Office Box 7068 Pasadena, CA 91109-7068 September 9, 2002

## Commissioner:

Please amend the above-identified application as folllows:

## In the Specification:

Page 16, lines 13 through 27, replace with the following:

Subsequently, the signs of all the defect candidates in the signed two-time judged defect candidate map 208 are judged in step 209, and the defect candidate 61F with one of the signs (in this case +) is left as a defect candidate. As for the defect candidates 62F and 63F with the other sign (in this case -), the absolute values of the signed differential images thereof provided in step 203 are compared in step 210 with the second threshold value that is greater than the first threshold value, and included among the defect candidates if the second threshold value is exceeded. In this manner, the one-bit defect candidate map can be finally obtained. When the